PLD Target Manipulator



PVD Products provides custom engineering for UHV PLD target manipulators to fit your deposition chamber. These manipulators are based on a single, co-axial, Ferro Fludic rotary feedthroughs. Target assemblies incorporate silicon nitride bearings and provide extended life even at high rotational speeds or high substrate temperatures. Hollow shafts on the target assemblies reduce heat transfer to the gears and bearings and provide for longer operating times. The feedthrough does not use any rotary-bellows seals, which might fail during continuous use. This manipulator requires only one penetration through the mother-flange, to provide more flexibility in properly locating the target assembly within your PLD chamber. Multi-Layer Versatility at your finger tips.



Custom TM assembly with eight 1" diameter targets. Includes Zstage and loadlock chamber assembly.



Solid model of a Target Manipulator holding four 2-inch diameter targets with optional water-cooled shield and computer driven stepper motors to index (change) the active target. Units come with Smart Motors coupled to supplied software. Software can index and rotate targets as well as provide target toggling if required. Water-cooled shields are available to protect both the active and inactive targets from vapor back -scattered by background gas, as well as thermal radiation from substrate heaters. Target assemblies are designed to provide easy target replacement.

Manual target indexing with détentes is provided to indicate proper target position, or an optional computer-controlled stepper motor system is available.

PLD Target Manipulator Features

- Multiple configurations all UHV compatible
- Co-axial, Ferro Fluidic rotary feedthrough
- Design provides for easy target changes
- Water-cooled target shielding for high temperature applications
- Automated target indexing with LabVIEWTM software control

Custom Target Manipulator Configurations:

Custom configurations are available on request for target diameters ranging from 12 to 300 mm. Target thickness up to 12 mm can be accommodated. Assemblies can be mounted on flanges ranging in size from 2.75" (70-mm) to 16.5" (420-mm). To obtain a quote for your specific needs, please refer to the adjacent figure and provide us with the following information:

- Number, diameter, and thickness of targets (N, d, t) •
- Orientation of targets within the deposition chamber • -Horizontal or Vertical (H, V), or at specified angle (θ)
- Mother flange Diameter (D2)
- Distance from vacuum surface to target surface (L) •
- Distances from the center of the mother flange to the center of the active target (L_V, L_H)
- Slot length and width (I, w)
- Slot orientation
- Laser beam position.

The customer is responsible for providing PVD Products with any information regarding space restrictions within the customer's chamber. Once a manipulator has been completely specified, PVD Products will provide the customer with a computer-aided 3-D solid model for the customer to approve prior to fabrication.

Standard Specifications:

Target rotational speeds: Electrical requirements: Max. bake-out temperature: For optional water cooled stage: Water requirements:

Variable from 5 to 50 RPM 100-120 VAC, 50/60Hz, 4A (Software control option) SCU-1000 Electronic drive unit: 19" rack mount x 3.5" high x 18" deep 200°C with

0.5 GPM, 75 PSI max, filtered, 27°C 1/4" SwagelokTM fittings external to the chamber

Options:

Water-cooled target shield with slot for laser and plume

- Z-axis target motion: Adds 50-mm (or larger) stroke to the target assembly from the base of the mother flange within the deposition chamber using a bellows-sealed stage. The overall length external to the chamber is increased by 4.5". A motor drive unit for the stage is available at additional cost.
- Internal Z-axis target height adjustment: Allows up to 25 mm of target height and watercooled shield adjustment (adjustment made internal to chamber, or with manipulator assembly on the bench)

Computer-controlled motor drive for target indexing as well as excimer laser functions Shutter assemblies

Support shafts for vertical target mounting configurations

User specified accessory ports on main flange for shutters, bias rings, etc.

Higher target rotational speed

